

<b>INFORMATION DISCLOSURE</b> <b>STATEMENT BY APPLICANT</b> (Multiple sheets used when necessary) SHEET 1 OF 1	Application No.	10/781,574
	Filing Date	February 17, 2004
	First Named Inventor	Hujanen et al.
	Art Unit	1773
	Examiner	Kevin M. Bernatz
Attorney Docket No.		ASMMC.032DV1

U.S. PATENT DOCUMENTS					
Examiner Initials	Cite No.	Document Number Number - Kind Code (if known) Example: 1,234,567 B1	Publication Date MM-DD-YYYY	Name of Patentee or Applicant	Pages, Columns, Lines Where Relevant Passages or Relevant Figures Appear
<i>MB</i>		6,700,752 B2	03-02-2004	Dimitrov et al.	

FOREIGN PATENT DOCUMENTS						
Examiner Initials	Cite No.	Foreign Patent Document Country Code-Number-Kind Code Example: JP 1234567 A1	Publication Date MM-DD-YYYY	Name of Patentee or Applicant	Pages, Columns, Lines Where Relevant Passages or Relevant Figures Appear	T <sup>1</sup>

NON PATENT LITERATURE DOCUMENTS			
Examiner Initials	Cite No.	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	T <sup>1</sup>
<i>MB</i>		"ALD technology is in the process of taking off ASAP," <a href="http://www.micromagazine.com">www.micromagazine.com</a> , 2005, 5 pages.	
<i>11</i>		Paranjpe et al., "Atomic layer deposition of AlO <sub>x</sub> for thin film head gap applications," <u>Journal of The Electrochemical Society</u> , 2001, pp. G465-G471, Vol. 148, No. 9.	

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Examiner Signature <i>Kevin M. Bernatz</i>	Date Considered <i>10/14/05</i>
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\*Examiner: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

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